

Chapter Five

Conclusion And Recommendations

5.1 Conclusion

The modeling was used to simulate the mechanical behavior of a MEMS cantilever which is used for the detecting of blood glucose concentration. ANSYS package was found to be a powerful tool for simulation analysis for the Piezoresistive Microcantilever .The deflection under surface pressure for different thicknesses of the Piezoresistive Microcantilever was obtained.

5.2 Recommendations

1. The results obtained by simulation need to be verified experimentally.
2. Also it is recommended to use another semi-conductor material to build the Piezoresistive Microcantilever for Glucose Sensing in order to obtain the most efficient Sensor .

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